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CLAIMS:

What is claimed is:

1. A method for depositing an inorganic material from a reactive solution onto a substrate, comprising:

5 chemically treating said substrate to activate growth of said inorganic material; immersing said substrate into said reactive solution; and

regenerating said reactive solution to allow for continued growth of said inorganic material onto said substrate.

- 2. The method of claim 1 wherein the inorganic material is a silicon oxide.
- 10 3. The method of claim 1 wherein the substrate is a silicon wafer.
 - 4. The method of claim 1 wherein the substrate is a component of a semiconductor chip.
 - 5. The method of claim 1 wherein the substrate is a component of a nano-based chip.
 - 6. The method of claim 1 wherein the inorganic material forms an optical waveguide.
 - 7. The method of claim 1 wherein the reactive solution is comprised of H_2SiF_6 and H_2O .
- 15 8. The method of claim 1 wherein the reactive solution is regenerated by the addition of silicon.
 - 9. An apparatus for depositing an inorganic material from a reactive solution onto a substrate comprising:

a first container;

20 said reactive solution disposed within said first container;

said substrate immersed in said reactive solution;

a second container:

a quantity of silica disposed within said second container; and

a means for adding a portion of said quantity of silica to said reactive solution.

- 25 10. The apparatus of claim 9 whereby the means for adding said portion of said quantity of silica to said reactive solution is a pump in fluid communication with said first container and said second container.
 - 11. The apparatus of claim 9 wherein the inorganic material is a silicon oxide.
 - 12. The apparatus of claim 9 wherein the substrate is a silicon wafer.
- 30 13. The apparatus of claim 9 wherein the reactive solution is comprised of H₂SiF₆ and H₂O.
 - 14. The apparatus of claim 9 further comprising:
 - a third container; and
 - a second quantity of silica disposed within said third container.

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15. The apparatus of claim 14 whereby the means for adding said portion of said quantity of silica to said reactive solution is a pump in fluid communication with said first container and said third container.